## Playing with the temporal shape of a high-power nanosecond1064 nm laser pulse to explore EUV generation and differentMARCNLdroplet deformation regimes.

Zeudi Mazzotta<sup>1,\*</sup>, Randy Meijer<sup>1,2</sup>, Dmitry Kurilovich<sup>3</sup>, Ruben Schupp<sup>1</sup>, Oscar Versolato<sup>1</sup>, Kjeld S. E. Eikema<sup>1,2</sup>, and Stefan Witte<sup>1,2</sup>

<sup>1</sup> Advanced Research Center for Nanolithography, Science Park 106, 1098 XG Amsterdam, The Netherlands <sup>2</sup> LaserLaB, Department of Physics and Astronomy, Vrije Universiteit, De Boelelaan 1081, 1081 HV Amsterdam, The Netherlands <sup>3</sup>ASML, De Run 6501, 5504 DR Veldhoven, The Netherlands



Target: tin droplets
study plasma formation and EUV generation on pico- and nanosecond time scale
Controlled preparation of tin droplets with temporally shaped pulses



Current technology uses a CO<sub>2</sub> laser, but:
requires a pre-pulse (second laser)
back reflections
issues with power scalability
We propose a 1064 nm Nd:YAG
Advanced technology
Control/Robust
Scalability/Availability
Temporal pulse shaping

GOAL: controlled EUV generation



[1] "High-energy Nd:YAG laser system with arbitrary sub-nanosecond pulse shaping capability", R. A. Meijer, A. S. Stodolna, K. S. E. Eikema and S. Witte, Optics Letters 42.14, 2758 (2017),
[2] "The transition from short to long timescale pre-pulses: laser-pulse impact on tin microdroplets", Randy A. Meijer, Dmitry Kurilovich, Oscar O. Versolato, and S. Witte (in preparation)
[3] "Efficient Generation of Extreme Ultraviolet Light From Nd:YAG-Driven Microdroplet-Tin Plasma", R Schupp et al, Phys. Rev. Applied 12, 014010 (2019).
[4] "Radiation transport and scaling of optical depth in Nd:YAG laser-produced microdroplet-tin plasma", R. Shupp et al, Appl. Phys. Lett. 115, 124101 (2019).

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![](_page_0_Picture_12.jpeg)

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